						Sheet 1 of 1	
FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S)  (Use several sheets if necessary)			ATTY DOCKET NO. 3230-86 APPLIC		CATION NO. 10/781,892		
			APPLICANT WU et al.				
Date Submitted to PTO: JUNE 9, 2004			FILING DATE February 20, 2004		GROUP 2811- 209 9 1		
U.S. PATENT DOCUMENTS							
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<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.